

## Process C1012 CMOS 1.0μm 5 Volt Digital

## **Electrical Characteristics**

T=25°C Unless otherwise noted

N-Channel Transistor	Symbol	Minimum	Typical	Maximum	Unit	Comments
Threshold Voltage	VT <sub>N</sub>	0.725	0.875	1.025	V	100x1.0µm
Body Factor	γ <sub>N</sub>		0.76		V <sup>1/2</sup>	100x1.0µm
Conduction Factor	β <sub>N</sub>	83	93	103	μA/V²	100x100µm
Effective Channel Length	Leff <sub>N</sub>		0.73		μm	100x1.0µm
Width Encroachment	$\Delta W_N$		0.81		μm	Per side
Punch Through Voltage	BVDSS <sub>N</sub>	10			V	
Poly Field Threshold	VTF <sub>P(N)</sub>	10			V	

P-Channel Transistor	Symbol	Minimum	Typical	Maximum	Unit	Comments
Threshold Voltage	VTP	-0.86	-1.01	-1.16	V	100x1.0µm
Body Factor	γ <sub>P</sub>		0.64		V1/2	100x1.0µm
Conduction Factor	β <sub>P</sub>	29.5	30.5	33.5	μA/V²	100x100µm
Effective Channel Length	Leff <sub>P</sub>		0.98		μm	100x1.0µm
Width Encroachment	$\Delta W_{P}$		0.75		μm	Per side
Punch Through Voltage	BVDSS <sub>P</sub>	-10			V	
Poly Field Threshold Voltage	VTF <sub>P(P)</sub>	-10			V	

Diffusion & Thin Films	Symbol	Minimum	Typical	Maximum	Unit	Comments
Well (field) Sheet Resistance	$\rho_{N-well(f)}$	0.565	0.644	0.720	KΩ/ロ	n-well
N+ Sheet Resistance	ρ <sub>N+</sub>	20	35	50	$\Omega/\Box$	
N+ Junction Depth	X <sub>jN+</sub>		0.45		μm	
P+ Sheet Resistance	ρ <sub>Ρ+</sub>	60	80	100	$\Omega/\Box$	
P+ Junction Depth	XjP+		0.5		μm	
Gate Oxide Thickness	T <sub>GOX</sub>	15.5	17.5	19.5	nm	
Field Oxide Thickness	T <sub>FIELD</sub>		700		nm	
Poly Sheet Resistance	$\rho_{POLY}$	15	22	30	$\Omega/\Box$	
Metal-1 Sheet Resistance	$ ho_{M1}$	25	45	655	mΩ/□	
Metal-2 Sheet Resistance	$\rho_{M2}$	15	25	35	mΩ/□	
Passivation Thickness	TPASS		200+900		nm	oxide+nit.

Capacitance	Symbol	Minimum	Typical	Maximum	Unit	Comments
Gate Oxide	Cox		1.97		fF/μm²	
Metal-1 to Poly1	C <sub>M1P</sub>		0.046		fF/μm²	
Metal-1 to Silicon	C <sub>M1S</sub>		0.028		fF/μm²	
Metal-2 to Metal-1	Смм		0.038		fF/μm²	

## Process C1012

Starting Material	P <100>	N+/P+ Width/Space	2.0 / 1.2μm
Starting Mat. Resistivity	25 - 50 Ω-cm	N+ To P+ Space	5.0µm
Typ. Operating Voltage	5V	Contact To Poly Space	1.0µm
Well Type	N-well	Contact Overlap Of Diffusion	1.0µm
Metal Layers	2	Contact Overlap Of Poly	0.8µm
Poly Layers	1	Metal-1 Overlap Of Contact	0.8µm
Contact Size	1.2 x 1.2μm	Metal-1 Overlap Of Via	0.8µm
Via Size	1.2 x 1.2μm	Metal-2 Overlap Of Via	0.8µm
Metal-1 Width/Space	1.4 / 2.4µm	Minimum Pad Opening	65 x 65µm
Metal-2 Width/Space	2.0 / 1.4µm	Minimum Pad-to-Pad Spacing	5.0µm
Gate Poly Width/Space	1.0 / 1.4µm	Minimum Pad Pitch	80.0µm

## **Physical Characteristics**